

Titanium Sublimation Pumping (TSP)



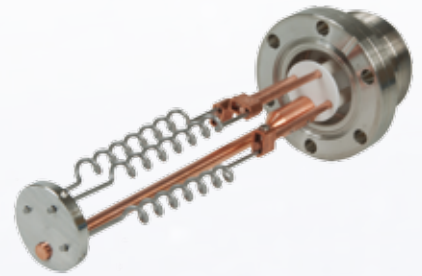
Titanium Sublimation Pumping

Remove reactive gases from the vacuum

Titanium Sublimation Pumps (TSPs) are often used in combination with ion pumps or independently to remove reactive gases from the vacuum environment. Combined with an ion pump, the TSP allows for low ultimate pressures in a shorter amount of time. All TSP components are bakeable to 400°C.

TSP Filament Cartridge

The filament cartridge is mounted on a 2- 3/4" CFF (NW 35). The feedthrough supports three titanium-molybdenum filaments and a return path for ground isolation. Each filament contains 1.5 grams of usable titanium and averages 20 hours of operation.



Liquid Cryoshroud

The liquid cryoshroud consists of a double walled, type 304L stainless steel cylinder with two liquid nitrogen feedthroughs (.375 in. diameter) with flare type fittings. It provides 1578 cm² (245 in.²) of liquid nitrogen cooled surface area that provides pumping speeds up to 12,000 l/s for hydrogen (see table). The shroud is mounted on an 8 in. CFF (DN 150).

Ambient Sputter Shield

The ambient sputter shield economically maximizes surface area when cooling is not practical or possible. It provides 827cm² (128 in.²) of ambient temperature surface area that provides pumping speeds up to 2200 l/s for hydrogen (see table). The shield is mounted on an 8 in. CFF (DN 150) or a 6 in. CFF (NW 100).



DIGITEL™ TSP/NEG Controller

A TSP or NEG can be fully operated from the LCD touchscreen of the QPC or MPC. They can be fired manually or automatically based on the pressure of either ion pump the controller is monitoring. Timed modes also let the user have full control over exact parameters of operation. A single remote controller can operate up to eight TSP filaments or two NEG pumps.

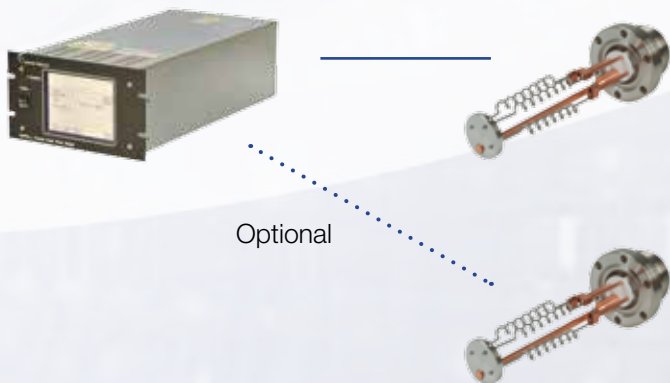
ing (TSP) vacuum environment

DIGITEL™ Flexibility

The DIGITEL™ line is flexible enough to control a wide variety of ion pump and TSP configurations. The LPCe and MPC can operate up to four ion pumps simultaneously or independent operation of one or two ion pumps respectively. The MPC is capable of controlling one or two TSP/NEG cartridges independently from the Remote TSP/NEG controller or internal TSP (ITSP).

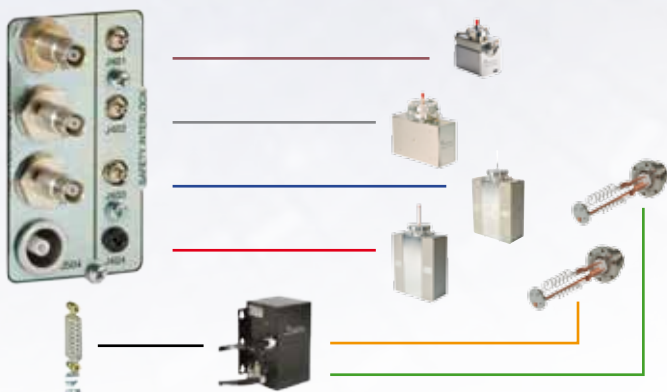
Example Configuration 1

Single or dual TSP operation from the TSP/NEG Controller.



Example Configuration 2

Three parallel diode ion pumps, one triode ion pump, and dual TSP/NEG operation from the MPC.

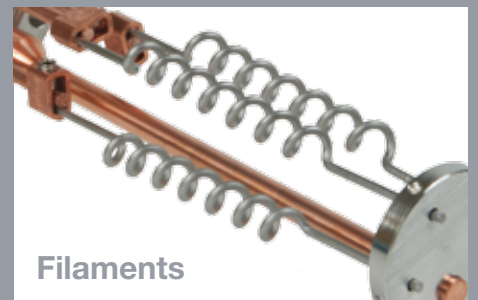


Benefits



Ease of Use

The TSP/NEG and MPC controllers are each fully controlled with an intuitive touch panel LCD.



Filaments

Each titanium-molybdenum filament contains 1.5 grams of usable titanium and averages 20 hours of operation.



Connectivity

TSP/NEG cables have MS style connectors that are bakeable and radiation resistant.



Safety

High currents travel over distances up to 10 meters through bakeable and radiation-resistant insulated and strain relief cabling.

Technical Data

| Specifications | | DIGITEL TSP/NEG | Remote TSP/NEG |
|---------------------------------|----------------------|--|--|
| Input Power | Voltage | 90-130 or 200-240 volts | 90-130 or 200-240 volts |
| | Frequency | 48-62 Hz | 48-62 Hz |
| Output Power | Independent Outputs | 1 | 1 |
| | Open Circuit Voltage | +17 vac | +17 vac |
| | Current (maximum) | 55A | 55A |
| | Watts (maximum) | 800 (max) | 800 (max) |
| | Resolution | 0.1A | 0.1A |
| High Current Connections | | 1-2 MS Style, Configurable | 1-2 MS Style, Configurable |
| Display | Type | 1/4 VGA touchscreen LCD | touchscreen LCD via MPC/QPC |
| | Readouts | Current, on-time, and programmable options | Current, on-time, and programmable options via MPC/QPC |
| Analog Outputs | Voltage | linear configurable | linear configurable |
| | Current/Pressure | linear or logarithmic, configurable | linear or logarithmic, configurable |
| Control Modes | | Manual, programmed, or remote | Manual, programmed, or remote |
| Communications | | Local/Remote/Full | Local/Remote/Full via MPC/QPC |
| | | Ethernet | Ethernet via MPC/QPC |
| | | Serial: 232, 422, 485 | Serial: 232, 422, 485 via MPC/QPC |
| Conformity to Norms | | EN 55011 Class A, IEC 801-2 | EN 55011 Class A, IEC 801-2 |
| | | EN 801-3, IEC 801-4, EN 61010-1 | EN 801-3, IEC 801-4, EN 61010-1 |
| Weight, kg (lbs) | | 16.8 (37) | 13.1 (29) |
| Size | | 3U high, 1/2 rack wide | 293 x 219 x 130 mm (min) |
| | | 438 mm (17.2 in.) deep | (12 x 9 x 5 in) |
| Additional Features | | | 293 x 219 x 150 mm (max) |
| | | | (12 x 9 x 6 in) |
| | | TSP Enable | TSP Enable via MPC/QPC |

Typical TSP Pumping Speeds

| | | | H ₂ | | CO | | H ₂ O | |
|--------------------------------|--------------------------------------|-------------|------------------------|--------|------------------------|-------|------------------------|--------|
| | Area | Temperature | Rate | Speed | Rate | Speed | Rate | Speed |
| | (cm ² /in. ²) | (°C) | (L/S/CM ²) | (L/S) | (L/S/CM ²) | (L/S) | (L/S/CM ²) | (L/S) |
| Liquid Cryoshroud (8 in.) | 709/110 | 20° C | 2.6 | 1,843 | 8.2 | 5,814 | 7.3 | 5,176 |
| | 1578/245* | -195° C | 17 | 12,053 | 11 | 7,799 | 14.6 | 23,039 |
| Ambient Sputter Shield (8 in.) | 827/128 | 20° C | 2.6 | 2,150 | 8.2 | 6,780 | 7.3 | 6,037 |
| Ambient Sputter Shield (6 in.) | 621/96 | 20° C | 2.6 | 1,614 | 8.2 | 5,092 | 7.3 | 4,533 |

*Applies to H₂O speed only.



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